AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims

1. (Cancelled)

2. (New) A method of programming a PMOS stacked-gate memory cell, wherein the memory cell includes a p-type source region in n-type semiconductor substrate, a p-type drain region formed in the n-type semiconductor substrate material and space-apart from the p-type source region to define a substrate channel region therebetween, a conductive floating gate electrode formed over the substrate channel region and separated therefrom by gate dielectric material, and a conductive control gate electrode formed over the floating gate electrode and separated therefrom by integrate dielectric material, the programming method comprising:

applying a negative voltage potential to the p-type drain region;

applying a voltage potential to the control gate electrode such that electrons are attached to the floating gate electrode from the p-type drain region through the gate dielectric material;

establishing a correlation between floating gate injection current and semiconductor substrate material current;

monitoring the value of the semiconductor substrate material current; and utilizing the monitored value of the semiconductor substrate material current to provide a feedback correction signal to the voltage potential applied to the control gate electrode such that the semiconductor substrate material current is maximized during programming of the memory cell.

3. (New) A programming method as in claim 2, and wherein the stacked-gate memory cell is included in a memory cell array comprising a plurality of such stacked-gate memory cells

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formed in n-type semiconductor substrate material, and wherein the monitored value is obtained from the memory cell array.

- 4. (New) A programming method as in claim 2, and wherein the stacked-gate memory cell is included in a memory cell array comprising a plurality of such stacked-gate memory cells formed in n-type semiconductor substrate material, and wherein the monitored value is obtained from a single stacked-gate memory cell.
- 5. (New) The programming method of claim 2, and wherein the semiconductor material is n-type silicon.
- 6. (New) The programming method of claim 5, and wherein the gate dielectric material is silicon dioxide.
- 7. (New) The programming method of claim 6, and wherein the floating gate electrode is polysilicon.
- 8. (New) The programming method of claim 7, and wherein the control gate electrode is polysilicon.